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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/727,187	12/02/2003	Michael D. Jack	901.0116.U1	4988
75	90 12/20/2005		EXAM	INER
Raytheon Office of General Counsel			POLYZOS, FAYE S	
William C. Schu Building B/1, M			ART UNIT	PAPER NUMBER
Goleta, CA 93117			2884	
			DATE MAILED: 12/20/2009	5

Please find below and/or attached an Office communication concerning this application or proceeding.

_		Application No.	Applicant(s)			
Office Action Summary		10/727,187	JACK ET AL.			
		Examiner	Art Unit			
		Faye Polyzos	2884			
Period fo	The MAILING DATE of this communication apport Reply	ears on the cover sheet with the	correspondence address			
WHI(- Exte after - If NC - Failt Any	CORTENED STATUTORY PERIOD FOR REPLY CHEVER IS LONGER, FROM THE MAILING DAINS of time may be available under the provisions of 37 CFR 1.13 SIX (6) MONTHS from the mailing date of this communication. O period for reply is specified above, the maximum statutory period we use to reply within the set or extended period for reply will, by statute, reply received by the Office later than three months after the mailing ed patent term adjustment. See 37 CFR 1.704(b).	ATE OF THIS COMMUNICATION 36(a). In no event, however, may a reply be ting will apply and will expire SIX (6) MONTHS from a cause the application to become ABANDONE	N. mely filed n the mailing date of this communication. ED (35 U.S.C. § 133).			
Status						
1)⊠	Responsive to communication(s) filed on <u>02 De</u>	<u>ecember 2003</u> .				
2a)□	This action is FINAL . 2b)⊠ This	action is non-final.				
3)[3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits					
	closed in accordance with the practice under E	x parte Quayle, 1935 C.D. 11, 4	53 O.G. 213.			
Disposit	ion of Claims		i			
5)□ 6)⊠ 7)□	Claim(s) <u>1-13</u> is/are pending in the application. 4a) Of the above claim(s) is/are withdraw Claim(s) is/are allowed. Claim(s) <u>1-13</u> is/are rejected. Claim(s) is/are objected to. Claim(s) are subject to restriction and/or	vn from consideration.				
Applicat	ion Papers					
· —	The specification is objected to by the Examine The drawing(s) filed on <u>06 April 2004</u> is/are: a) Applicant may not request that any objection to the of Replacement drawing sheet(s) including the correction	☑ accepted or b)☐ objected to drawing(s) be held in abeyance. Se	ee 37 CFR 1.85(a).			
11)□	The oath or declaration is objected to by the Ex	,	•			
Priority ι	under 35 U.S.C. § 119		,			
a)l	Acknowledgment is made of a claim for foreign All b) Some * c) None of: 1. Certified copies of the priority documents 2. Certified copies of the priority documents 3. Copies of the certified copies of the priorical application from the International Bureau See the attached detailed Office action for a list of	s have been received. s have been received in Applicat ity documents have been receiv (PCT Rule 17.2(a)).	ion No ed in this National Stage			
Attachmen	t(s)					
	e of References Cited (PTO-892)	4) Interview Summary				
3) 🔯 Infori	ee of Draftsperson's Patent Drawing Review (PTO-948) mation Disclosure Statement(s) (PTO-1449 or PTO/SB/08) r No(s)/Mail Date 12/2/03.	Paper No(s)/Mail D 5) Notice of Informal F 6) Other:	ate Patent Application (PTO-152)			

DETAILED ACTION

Claim Rejections - 35 USC § 102

1. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 2. Claim 1-6 and 8-9 are rejected under 35 U.S.C. 102(b) as being anticipated by Rice et al. (Journal paper entitled "High-Tc Superconducting Antenna-coupled Microbolometer on Silicon").

Regarding claim 1, Rice discloses a radiation sensor comprising: a substrate (page 98, lines 2 of 3rd paragraph); an antenna supported by the substrate (Fig. 1a and page 99, 1st paragraph under the heading "Design"); a thermal detector unit (i.e. microbolometer) spaced from the antenna and from the substrate (Fig. 1b and 3b); a multi-layered conductive lead comprises a superconductive layer in electrical contact with the thermal detector unit and the antenna, and a support layer between the superconductive layer and the substrate (page 99 1st paragraph under the heading "Design").

Regarding claims 2-4, Rice discloses the conductive lead comprises a buffer layer, comprises Yttria stabilized Zirconia, disposed between the support layer and the superconductive layer characterized by a thermal conductivity K<0.1 W/cm-K (page 98 1st paragraph under the heading "Abstract").

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Regarding claims 5-6, Rice discloses the buffer layer defines a thermal conductivity that is less than one order of magnitude greater than a thermal conductivity defined by the superconductive layer (page 99 1st paragraph).

Regarding claim 8, Rice discloses a radiation sensor for measuring incident radiation comprising a substrate defining a cavity (page 98, lines 2 of 3rd paragraph); a thermal detector unit (i.e. microbolometer) disposed above the cavity (Fig. 1b and 3b), an antenna coupled to the substrate (Fig. 1a and page 99, 1st paragraph under the heading "Design"); and a conductor in contact with the antenna and the thermal detector unit, the improvement comprising: the conductor defining a plurality of layers and comprising: a superconductor layer; a support layer between the conductive layer and the substrate; and a buffer layer between the support layer and the superconductive layer (Fig. 1b and 3b and page 99 1st paragraph under the heading "Design").

Regarding claim 9, Rice discloses a radiation sensor for measuring incident radiation comprising a substrate defining a cavity (page 98, lines 2 of 3rd paragraph); a thermal detector unit (i.e. microbolometer) disposed above the cavity (Fig. 1b and 3b), an antenna coupled to the substrate (Fig. 1a and page 99, 1st paragraph under the heading "Design"); and a conductor in contact with the antenna and the thermal detector unit, the improvement comprising: the conductor defining a multi-layer structure and comprising: a support layer adjacent to the substrate; a superconductive layer opposite the substrate; and a buffer layer between the support layer and the superconductive elayer (Fig. 1b and 3b and page 99 1st paragraph under the heading "Design").

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Claim Rejections - 35 USC § 103

- 3. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 4. Claim 7 is rejected under 35 U.S.C. 103(a) as being unpatentable over *Rice et al.*(Journal paper entitled "High-Tc Superconducting Antenna-coupled Microbolometer on Silicon") as applied to claim 1 above, and further in view of *Ooms et al* (US 6,563,118 B2).

Regarding claim 7, Rice discloses a radiation sensor comprising: a substrate (page 98, lines 2 of 3rd paragraph); an antenna supported by the substrate (Fig. 1a and page 99, 1st paragraph under the heading "Design"); a thermal detector unit (i.e. microbolometer) spaced from the antenna and from the substrate (Fig. 1b and 3b); a multi-layered conductive lead comprises a superconductive layer in electrical contact with the thermal detector unit and the antenna, and a support layer between the superconductive layer and the substrate (page 99 1st paragraph under the heading "Design"). Rice does not disclose of the superconductive layer selected from a group of perovskite superconductors. Ooms discloses semiconductive layer consisting of perovskite superconductors (col. 1, lines 14-21). Ooms teaches various metallic oxides, such as perovskites, exhibit desirable characteristics such as piezoelectric, pyroelectric, ferroelectric, ferromagnetic, colossal magnetic resistance and super conductive properties. Such oxides may be included or used in connection with microelectronic

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devices that take advantage of these characteristics (col. 1, lines 14-21). Therefore, it would have been obvious to modify the radiation sensor disclosed by Rice, to include a semiconductor layer consisting of perovskite superconductors, as disclosed supra by Ooms, to allow for a more versatile apparatus.

5. Claims 10-13 are rejected under 35 U.S.C. 103(a) as being unpatentable over Rice et al. (Journal paper entitled "High-Tc Superconducting Antenna-coupled Microbolometer on Silicon") and Luukanen et al (US 2003/0222217 A).

Regarding claim 10, Rice discloses of a method for making a radiation sensor comprising: a substrate (page 98, lines 2 of 3rd paragraph); an antenna supported by the substrate (Fig. 1a and page 99, 1st paragraph under the heading "Design"); a thermal detector unit (i.e. microbolometer) spaced from the antenna and from the substrate (Fig. 1b and 3b); a multi-layered conductive lead comprises a superconductive layer in electrical contact with the thermal detector unit and the antenna, and a support layer between the superconductive layer and the substrate (page 99 1st paragraph under the heading "Design"). Rice does not specifically disclose of a method to deposit the filler material within the cavity. Luukanen discloses depositing a filler material within the cavity of the substrate (301); depositing a thermal detector unit (i.e. microbolometer) onto the filler material; depositing an antenna (102, 103) onto the substrate (301); depositing a multi-layer conductive lead to contact the thermal detector unit and the antenna, wherein the multi-layer conductive lead defines a layer of superconductive material; and conductively bonding a first segment of the conductive lead to the antenna to form an electrically conductive pathway between the

superconductive material and the antenna, and a second segment of the conductive lead to the thermal detector unit so as to form an electrically conductive pathway between the superconductive layer and the thermal detector unit (paragraphs [0033]-[0034]). Luukanen teaches after patterning, a layer of low-T_c superconductive material is deposited onto the patterned surface and excess resist and the unwanted remnants of the material are washed away in a solvent, leaving only the required patterns on top of the surface of the sacrificial layer (paragraph [0033]). Therefore, it would have been obvious to modify the method suggested by Rice, to incorporate a depositing of filler material method, as disclosed supra by Luukanen, to allow for a more versatile radiation sensor.

Regarding claim 11, Luukanen discloses the method comprising a removing the filler material (paragraph [0033]).

Regarding claim 12, Luukanen discloses depositing a thermal detector unit comprises depositing a thermally reactive material over at least a portion of the filler material and delineating edges thereof to define the thermal detector unit (See Abstract and paragraph [0033]).

Regarding claim 13, Luukanen discloses depositing an antenna (102)(103) onto the substrate (301) comprises depositing a conductive material onto the substrate and delineating edges thereof to define the antenna (See Abstract and paragraphs [0006] and [0033]).

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Conclusion

6. The prior art made of record and not relied upon is considered pertinent to

applicant's disclosure.

7. Any inquiry concerning this communication or earlier communications from the

examiner should be directed to Faye Polyzos whose telephone number is 571-272-

2447. The examiner can normally be reached on Monday thru Friday from 7:30 AM to

4:00 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's

supervisor, Dave Porta can be reached on 571-272-2444. The fax phone number for

the organization where this application or proceeding is assigned is 571-273-8300.

8. Information regarding the status of an application may be obtained from the

Patent Application Information Retrieval (PAIR) system. Status information for

published applications may be obtained from either Private PAIR or Public PAIR.

Status information for unpublished applications is available through Private PAIR only.

For more information about the PAIR system, see http://pair-direct.uspto.gov. Should

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